

**AMENDMENTS TO THE CLAIMS:**

This listing of claims will replace all prior versions and listings of claims in the application:

1-16. (Canceled)

17. (Currently amended) A film-forming apparatus, comprising:

a dispenser nozzle arranged to face a target substrate to be processed so as to supply a chemical solution that includes a solid component and a solvent to said target substrate;

a suction nozzle arranged to face said target substrate for selectively sucking only a solvent vapor on a liquid film formed on said target substrate by the supply of a chemical solution from said dispenser nozzle;

a first moving section for relatively moving said target substrate and said dispenser nozzle; and

a second moving section for relatively moving said target substrate and said suction nozzle.

18. (Previously presented) The film-forming apparatus according to claim 17, further comprising a supply nozzle of gas flow for supplying a flow of gas to a liquid film formed on said target substrate.

19. (Original) The film-forming apparatus according to claim 17, wherein the length of the suction port of said suction nozzle in the longitudinal direction is larger than the diameter of said target substrate.

20-25. (Canceled)